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PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
702-002116SERIAL NO.
09/719,757INFORMATION DISCLOSURE STATEMENT
STATEMENT BY APPLICANT

APPLICANTS

Dirk E.M. VAN DYCK et al.

(Use several sheets if necessary)

FILING DATE
July 16, 2001GROUP
ART UNIT-not yet assigned

U.S. PATENT DOCUMENTS




EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

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FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	AQ	Jedrasik, P. et al. "Optimal filtering versus regularization methods in the Fourier precompensation based proximity neurocorrection in electron beam lithography," <i>Microelectronic Eng.</i> 41-42: 195-198 (1998)
	AR	Jedrasik P. "Neural networks application for fast, direct correction kernel generation for proximity effects correction in electron beam lithography," <i>Microelectronic Eng.</i> 27(1-4): 191-194 (1995)
	AS	Frye, R.C. "Adaptive neural network algorithms for computing proximity effect corrections," <i>J Vacuum Sci & Tech (Part B)</i> 9(6): 3054-3058 (1991)

EXAMINER



DATE CONSIDERED

7/22/04

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.